



THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : **Confirmation No. 9257**
Tetsuji TOGAWA et al. : Attorney Docket No. 2005_0993A
Serial No. 10/539,245 : Group Art Unit 3723
Filed March 29, 2006 : Examiner Maurina T. Rachuba
SUBSTRATE HOLDING MECHANISM, : **Mail Stop: AMENDMENT**
SUBSTRATE POLISHING APPARATUS AND
SUBSTRATE POLISHING METHOD

PETITION FOR EXTENSION OF TIME

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Petition hereby is made for a one month extension of time to respond to the communication of September 25, 2007.

The fee of \$120.00 is

- ☒ submitted herewith.
☐ to be charged to Deposit Account No. 23-0975. A duplicate copy of this Petition is enclosed.
- ☐ Small entity status of this application is established by a Small Entity Status Assertion which
- ☐ is enclosed.
☐ has been previously submitted.
☐ has been previously asserted.

Respectfully submitted,

Tetsuji TOGAWA et al.

By

Nils E. Pedersen

Registration No. 33,145

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January 25, 2008

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